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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Complete if Known

Application Number	10/664,247
Filing Date	09/17/2003
First Named Inventor	Diane K. Sewart
Art Unit	
Examiner Name	
Attorney Docket Number	F118 B

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U. S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
	E	05-174768	07-13-1993	Nikon Corp.		

Examiner Signature	/Stephen Rosasco/	Date Considered	03/17/2008
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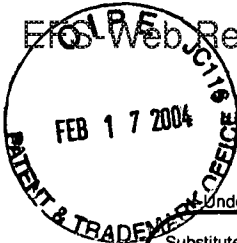
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Examiner Name	
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Sheet

2

of

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NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	F	C.K. CRAWFORD, Charge Neutralization Using Very Low Energy Ions, Scanning Electron Microscopy, 1979, II, SEM INC., USA	
	G	ALBERT FOLCH ET AL., High Vacuum Versus, "Environmental" Electron Beam Deposition, Jul/Aug. 1996, B 14(4), PP. 2609-2614, J. Vac. Sci.	
	H	YUKINORI OCHIAI, Electron-Beam-Induced Deposition of Copper with Low Resistivity, Nov/Dec. 1996, B 14(6), PP. 3887-3891, J. Vac. Sci. Technol	

Examiner Signature	/Stephen Rosasco/	Date Considered	03/17/2008
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